



COPY

Docket No.: A-69175-1/MSS (463035-650)

UNITED STATES PATENT AND TRADEMARK OFFICE

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| First Named Inventor: | Nam P. Suh et al. | |
| Appln. No.: | 10/029,158 | |
| Filing Date: | December 21, 2001 | Examiner: RACHUBA, Maurina T. |
| Title: | APPARATUS AND METHOD FOR CHEMICAL MECHANICAL POLISHING OF SUBSTRATES | Group Art Unit: 3723 |

PETITION FOR EXTENSION OF PERIOD FOR RESPONSE

Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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OCT 21 2004
TECHNOLOGY CENTER R3700

Dear Sir:

Pursuant to 37 C.F.R. § 1.136(a), Applicant hereby petitions for an extension of 2-month(s) (from July 13, 2004 to September 13, 2004) within which to respond to the Office Action dated April 13, 2004. A check in the amount of \$564.00 (\$144 for additional claims fee, \$420 for 2 month extension fee for large entity) is enclosed herewith to cover the extension fee. Please charge any additional fees or credit any overpayment to our Deposit Account No. 50-2319 (Order No. A-69175-1/MSS (463035-650)).

Respectfully submitted,
DORSEY & WHITNEY LLP

Date: September 13, 2004

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